

**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Jung-Wook Kim, et al.

Examiner: Michail Kornakov

Serial No: 10/606,512

Group Art Unit: 1746

Filed: June 26, 2003

Docket: 8054-23 (AW8037US/JJ)

For: **METHOD FOR CLEANING A PROCESSING CHAMBER AND METHOD  
FOR MANUFACTURING A SEMICONDUCTOR DEVICE**

Mail Stop: Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Sir:

In response to the Office Action dated September 27, 2006, please amend the above-referenced patent application as set forth herein.

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